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Patent
Attorney's Docket No. 032501-006

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
NGOI et al.) Group Art Unit: 2877
Application No.: 09/407,177) Examiner: Hwas Lee
Filed: September 28, 1999) Confirmation No.: 2405
For: HETERODYNE)
INTERFEROMETRY FOR SMALL)
SPACING MEASUREMENT)

AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated March 28, 2002, please amend the above-identified patent application as follows:

IN THE CLAIMS

Please substitute amended claims 1, 11, 16 and 26 as follows:

1. (Amended) A system for high speed and precision measurement of the

Q) distance between at least two near contact surfaces, one of which is an optically transparent element and the other is a substantially non-transparent element using heterodyne interferometry, comprising:

 a laser source, which produces an output having two superimposed orthogonally polarized beams having S and P polarization, with a frequency difference between them;